**Precision Etching Coating System**

**Equipment:** Precision Etching Coating System (PECS) Model 682 (Gatan)

**No. of Equipment:** UACH13

**Responsible coordinator:** Dr. Petr Svora

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**Equipment Description**

**Description of equipment:**

Precision etching coating system enables the etching of surfaces and coating of the surfaces by metals with small grains. This technique is suitable for transmission and scanning electron microscopy, also for light microcsopy.

**Specification of expertise relevant to NanoEnviCz workpackages:**

**WP3**a,c-h, **WP4**a,b, **WP5**c, **WP6**a,c-f, **WP7**a-e,g-i, **WP8**a,c-f

**Detailed description of expertise**

**Please, specify the main research topics connected with equipment**:

All the fields in which the characterization of the prepared materials is needed.

**Please, specify the secondary research topics connected with equipment**:

**Keywords describing research area:**

Sample preparation for transmission and scanning electron microscopy, also for light microcsopy.

**Competence**

**Relevance for applied and industrial research:**

High-quality materials characterization to support preparation of perspective novel materials in large scale production (applied and industrial research).

**Relevance for fundamental studies:**

Detailed analysis of prepared materials connection between morphology and properties in nanoscale range.